February 27, 1997

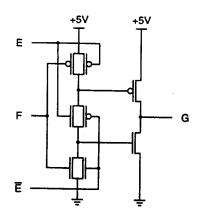
E.E. 451.3 VLSI Circuit Design

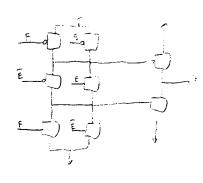
Page 3

QUESTION #1

MARKS: 10 (10)

a) Determine the operation of the following circuit. A truth table is required.







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a question."



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QUESTION #2

MARKS: 15 (3 + 3 + 3 + 3 + 3)

Explain briefly, but as completely as possible, FIVE (5) of the following. A SHORT paragraph should be sufficient.

The diffusion layer is usually not used as a signal routing layer. Give THREE (3) reasons for

ROUTING PROBLEMS (TRANSKIDER)

SPACE (# OF RULES)

The Metal 1 layer is usually used as the primary signal routing layer. Give THREE (3) reasons b) for this.

> LOW R } = FAST RUNS ANY WHERE SIMPLE RULES

Where is the Canadian Microelectronics Corporation (CMC) located? Who does their fabrication? Why do they do their fabrication?

> KINGSTON, ONTALIO (QUEEN'S UNIVERSITY) GENNUM, MITEL, NORTEL (MOSIS)

HILING POOL OF EDUCATED PROPLE

TAX BREAK

BOLTON Student Name:

Student Number:

ONE

this examination paper contain? Explain.

A T-GATE HAS A N-CHANNEL AND P-CHANNEL TRANSISTOR IN //. ONLY P3 AND N3 ARE CANNECTED LIKE THIS. MUST ALSO HAVE STOWNES THAT ARR COMPLEMENTS (E NO E).

Design rule D.1 indicates that the P-well to P+ Diff. Minimum Separation (see Appendix C: Available Process Technologies, page C9) is 14 design scale microns (dsm). Why is it so large? Using design rule D.1 as a start, what would the Minimum Separation design rule for Pwell to P+ mask be if one existed? Why?

> P+DIFF WILL SHORT TO P-WELL! MUST ALSO ALLOW FOR ISOLATION (P-GUARDS, ETC. 10 D.S.M. (FROM RULE C.B)

ENGLOSURE RULE FOR PT MASK OVER DRUKEWELL

- The CMOS fabrication process consists of a number of steps. Pick the ONE that you consider to be crucial to the success of fabrication. Discuss.
 - INGOT MANUFACTURE
 - MASKS (PREPARATION AND USE)
 - POLYSILICON DEPOSITION ETC.

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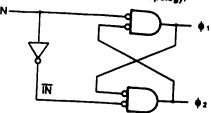
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[Prof] "This question is one I fully expected you guys to bugger up." [Student] "I didn't let vou down, sir."

QUESTION #3

▲MARKS: 20 (20)

All parts of this question concern a two-phase (2¢) clock generator. The operation of the circuit is NOT important for this exam, just the topology.



AB

a) Draw a STICKS diagram for the two-phase circuit.

When doing your diagram the following constraints must be followed:

- 1. Input must come in from the left (on Metal 1).
- 2. Outputs must exit from the right (on Metal 1).
- 3. No wires are allowed outside the VDD and Vss Power rails.
- 4. At least two substrate connections (of each type) must be shown.
- 5. No Metal 2 is allowed.
- 6. Standard STICKS colors for the CMOS3DLM technology must be used.

Use the following page for your final two-phase STICKS diagram (indicate clearly which one it s). Your STICKS diagram will be marked using "good CMOS circuit design" guidelines as discussed

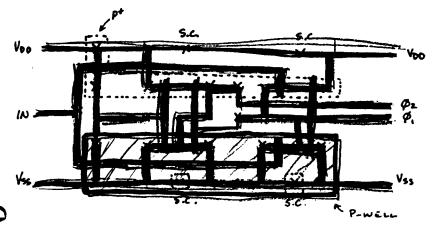


CONTACT CUTS!! (MINIMUM # = ZZ) SUBSTRATE CONNECTIONS P+ P-WELL

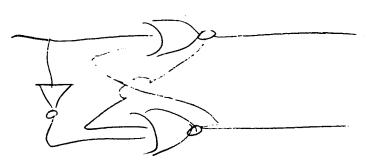
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"I try to set exams so you get no benefit from studying."



23 CONTACT CUTS (TOTAL) S.C. TO VOD (FOR P-CHANNELS) OUTSIDE PT S.C. TO VSS (FOR N-CHAWNELS) I WSIDE PT INSIDE PWELL



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